

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: OHMI, et al

Serial No.: 10/566,241

Filed: January 30, 2006

Title: Microwave Plasma Processing Method, Microwave Plasma Processing Apparatus, and It's Plasma Head

Art Unit:

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97 & 1.98Mail Stop: DD
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

May 30, 2006

Sir:

In the matter of the above-identified application, applicant(s) are submitting herewith copies of the documents listed in the attached Form(s) PTO/SB/08A and/or PTO/SB/08B for the Examiner's consideration.

This information disclosure statement is being submitted before the mailing date of a first office action.

To the extent that the documents listed on the attached form equivalent to Form(s) PTO/SB/08A and/or PTO/SB/08B are not in the English language, the requirement of 37 CFR 1.98(a)(3) for a concise explanation of the relevance is satisfied by an English language translation of the documents and the disclosure in the specification.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this

paper, including excess claim fees, to Deposit Account No. 01-2135 (1113.45832X00), and please credit any excess fees to such deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP



Melvin Kraus
Registration No. 22,466

MK/jla
1300 North Seventeenth Street
Suite 1800
Arlington, VA 22209
Telephone: (703) 312-6600
Fax: (703) 312-6666

PTO/SB/08B (04-03)
Approved for use through 10/31/2002. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE